

PTO/SB/08A (10-01)

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Substitute for form 1449A/PTO

## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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of 4

### Complete if Known

Application Number	10/619,940
Filing Date	July 14, 2003
First Named Inventor	Michalicek, M.A.
Art Unit	2872 2873
Examiner Name	Unassigned E. LESTER

Attorney Docket Number

19930-001410

### U.S. PATENT DOCUMENTS

Examiner	Cite No. <sup>1</sup>	Document Number Number Kind Code <sup>2</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
EE	AA	4,330,175	05-18-1982	Yohji Fujii et al.	
	AB	5,212,582	05-18-1993	William E. Nelson	
	AC	5,279,924	01-18-1994	Keiji Sakai et al.	
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	AY	2002/0118472 A1	08-29-2002	Edward A. Hill	

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Considered

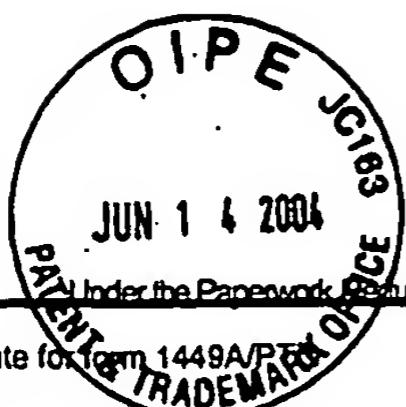
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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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### Complete if Known

Application Number	10/619,940
Filing Date	July 14, 2003
First Named Inventor	Michalicek, M. A.
Art Unit	2872 2873
Examiner Name	Unassigned E. LESTER

Attorney Docket Number

19930-001410

### U.S. PATENT DOCUMENTS

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E. LESTER	AZ	2002/0135850 A1	09-2002	Hagelin et al.	
	BA	6,449,096 B1	09-10-2002	Larry Fabiny et al.	
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E. LESTER	CD	6,608,712 B2	08-19-2003	M. Adrian Michalicek	

### FOREIGN PATENT DOCUMENTS

Examiner Initials <sup>1</sup>	Cite No. <sup>1</sup>	Foreign Patent Document		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
		Country Code <sup>3</sup>	Number <sup>4</sup> Kind Code <sup>5</sup> (if known)				
	CE						

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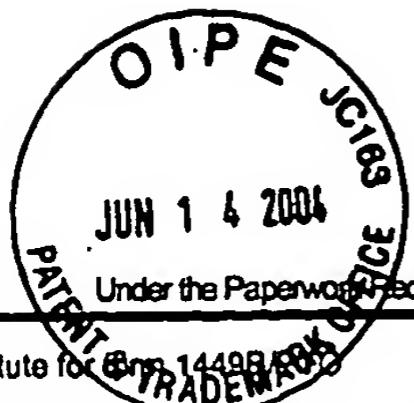
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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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### Complete if Known

Application Number	10/619,940
Filing Date	July 14, 2003
First Named Inventor	Michalicek, M. A.
Art Unit	2872-2873
Examiner Name	Unassigned E. LESTER

Attorney Docket Number

19930-001410

### OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
<i>EDL</i>	CF	T. Akiyama, et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993; pp.106-110	
	CG	C.M.A. Ashruf, et al., "Galvanic porous silicon formation without external contacts," Sensors and Actuators 74 (1999) pp. 118-122	
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	CJ	A.S. Dewa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical CrossConnect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96 <i>NO DATE AVAILABLE</i>	
	CK	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999	
	CL	J. Grade et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100	
	CM	Robert E. Hopkins, <i>Some Thoughts On Lens Mounting</i> , Optical Engineering, September-October 1976, Vol. 15, No. 5, pgs. 428-430.	
	CN	V. Kaajakari et al.; "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65	
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	CP	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 <sup>th</sup> May 1985	
	CA	P. Phillippe et al., "Wavelength demultiplexer: using echelle gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985	
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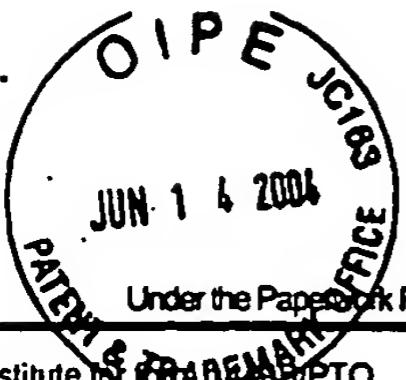
4-1-05

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Substitute for TRADEMARK PTO		Complete if Known	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>		Application Number	10/619,940
(use as many sheets as necessary)		Filing Date	July 14, 2003
		First Named Inventor	Michalicek, M. A.
		Art Unit	2872-2873
		Examiner Name	Unassigned E. LESTER
Sheet	4	of	4
		Attorney Docket Number	19930-001410

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
<i>EJL</i>	cs	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," <i>Appl. Phys. Lett.</i> 49 (12), 22 September 1986	
	CT	Z. J. Sun et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," <i>IEEE Photonics Technology Letters</i> , Vol. 10, No. 1, January 1998	
	CU	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202	
	CV	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," <i>J. Electrochem. Soc.</i> , Vol. 142, No. 6, June 1995	
	CW	P. VanKessel et al., "A MEMS-Based Projection Display," <i>Proceedings of the IEEE</i> , Vol. 86, No. 8, August 1998, pp. 1687-1704	
	CX	Microfabricated-Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998	
	CY	Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller, Spring 2000	
<i>EJL</i>	CZ	<i>Transducer Elements</i> , Piezo Systems, Inc., Cambridge MA, Catalog #3, 1998, pgs. 30-45.	

Examiner Signature	<i>EJ Lester</i>	Date Considered	4-1-05
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